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JiuBin Tan
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Contents

Part Two

Authors

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Introduction

We had the great honor of organizing the International Symposium on Optical Measurement Technology and Instrumentation. It was truly a great pleasure for us to greet the more than 1000 participants from many different countries who attended the symposium. We firmly believe the symposium will become an important international event in the field of optical technology.

The International Symposium on Optical Measurement Technology and Instrumentation was sponsored by the Chinese Society for Optical Engineering and China High-tech Industrialization Association (CHIA), organized by Chinese Society for Optical Engineering (CSOE), Photo-electronic Technology Committee, Chinese Society of Astronautics, Photo-electronic Industrialization Committee, CHIA, and Department of Cooperation and Coordination for Industry, Academe, and Research, CHIA.

The purpose of the symposium is to provide a forum for the participants to report and review the innovative ideas and up-to-date progress and developments, and discuss the novel approaches to application in the optical field. It is sincerely hoped that the research and development in optical field will be promoted, and the international cooperation sharing the common interest will be enhanced.

On behalf of other co-chairmen, and the Organization Committee, we would like to heartily thank our sponsors and cooperating organizers for all they have done for the symposium. Thanks also to all the authors for their contributions to the proceedings, to all of the participants and friends for their interest and efforts in helping us to make the symposium possible, to the Program Committee for their effective work and valuable advice, especially the Secretariat, and to the SPIE staff for their tireless efforts and outstanding service in preparing and publishing the proceedings.

Sen Han
Jiubin Tan